

AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITING PROCEDURE
EXAMINING GROUP 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:	Van Beek, <i>et al.</i>	Docket No.:	EPC-019
Serial No.:	10/578,026	Art Unit:	2829
Filed:	March 13, 2007	Examiner:	Karen M. Kusumakar
		Conf. No.:	4725
For:	Method of Manufacturing a MEMS Device and MEMS Device		

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 CFR § 1.116

Dear Sir:

Applicant respectfully submits the following amendments and remarks in response to Examiner's Office Action dated December 17, 2008, which Action is made final. Applicant respectfully requests that these amendments and remarks be entered in pursuant to the provisions of 37 CFR § 1.116, and respectfully request reconsideration of the claims.